

**Reply Under 37 C.F.R. § 1.116  
Expedited Procedure  
Technology Center 1700**

Attorney Docket No. 740756-2709

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)	
Koichiro TANAKA	)	Confirmation No. 9528
Application No. 10/769,820	)	Examiner: Samuel Heinrich
Filed: February 3, 2004	)	Group Art Unit: 1793
For: LASER IRRADIATION STAGE,	)	
LASER IRRADIATION OPTICAL	)	
SYSTEM, LASER IRRADIATION	)	
APPARATUS, LASER IRRADIATION	)	
METHOD, AND METHOD OF	)	
MANUFACTURING A	)	
SEMICONDUCTOR DEVICE	)	

**AMENDMENT WITH RCE**

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Final Office Action mailed December 28, 2007, and together with the Request for Continued Examination concurrently filed herewith, please amend the above-identified application as follows: